



843.43427X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: HASEGAWA et al
Serial No.: 10/762,548
Filed: January 23, 2004
For: Fabrication Method of Semiconductor Integrated
Circuit Device And Mask Fabrication Method
Art Unit: 1756
Examiner: S. Rosasco

AMENDMENT

Mail Stop: Amendment (Fee)
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

January 3, 2007

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application, in response to the Office Action dated September 1, 2006. The amendments are listed below and set forth on the following pages.

Amendments to the Specification; and

Remarks are included following the amendments.